IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Makoto AKIZUKI et al.

Serial No. [NEW]

Filed December 26, 2001

METHOD FOR FORMING GAS CLUSTER AND METHOD FOR FORMING THIN FILM

(Rule 1.53(b) Continuation of Serial No. 09/799,681, Filed March 7, 2001) Attn: APPLICATION BRANCH

Attorney Docket No. 2000-1897

CHANGE OF ADDRESS

Assistant Commissioner for Patents, Washington, D.C.

Sir:

Effective IMMEDIATELY, please note the following change of address

for the undersigned attorney of record:

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Respectfully submitted,

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MJ/pjm Washington, D.C. 20006 Telephone (202) 721-8200 December 26, 2001